Retaining System, Device and Method for Handling Substrate Stacks

Abstract

The invention relates to a retaining system (1, 20) for handling a first substrate (4) that is to be bonded with a second substrate (13) with:

- A retaining surface (1o, 20o) for retaining a first substrate (4), and
- At least one recess (2, 21), recessed relative to the retaining surface (1o, 20o), for retaining magnetically acting attachment means (5, 5', 5") for securing the first substrate (4) relative to a second substrate (13) that is aligned with the first substrate (4).

In addition, this invention relates to a device for handling a substrate stack (14), consisting of a first substrate (4) and a second substrate (13) that is aligned relative to the first substrate (4), with magnetically acting attachment means (5, 5', 5") for securing the first substrate (4) relative to the second substrate (13) in an aligned immobilized position.

This invention relates, moreover, to a corresponding method.

In this regard, see Figure 1.